



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): MATSUI

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Examiner: SHAKERI, H.

Title: METHOD AND APPARATUS FOR
MECHANO-CHEMICAL
POLISHING

Assistant Commissioner for Patents
Washington, D.C. 20231

Date: September 30, 2002

CERTIFICATE OF HAND DELIVERY

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AMENDMENT

Sir:

In response to the Office Action mailed May 16, 2002, please enter the following amendments and consider the appended remarks.

IN THE CLAIMS

Please cancel claims 45, 46, 66 and 72 - 73 without prejudice.

Please amend the claims as follows:

44. (Once Amended) A method for mechanochemical polishing, comprising:
preparing a chemical solution that includes hydrogen peroxide water and abrasive grains
made of chromium (III) oxide;
polishing a surface of a semiconductor wafer by mechanochemical polishing using the
chemical solution and a polishing cloth; and

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